# Laser-Enabled Directed Nanomanufacturing

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# **Topics**

- Laser nano/micromanufacturing
  - Laser Chemical Vapor Deposition
  - Directed growth of nanomaterials
- Laser-assisted electronic materials processing and device fabrication
  - Flexible electronics
- Laser interactions with biological materials
  - Surface patterning for cell growth
  - Fibrous material scaffolding

# Nanomachined patterns by femtosecond laser coupled to apertureless near field scanning optical microscope (NSOM)

Chimmalgi et al., Appl. Phys. Lett., (2003) J. Appl. Phys., (2005)

Hwang et al., Appl. Phys. A, (2009)

#### Nano-crystallization by apertureless NSOM

Chimmalgi, Nano Lett. (2005)

# In-situ TEM Imaging and NSOM Processing



# **Alternating Crystal Structure**



# Laser In-situ TEM Diagnostics & Processing



#### Laser-based Selective Nanowire growth

#### metal nanoparticle catalyzed silicon nanowire growth under VLS mechanism

VLS (Vapor-Liquid-Solid) Si nanowire growth

#### **Laser Illumination**

#### ••••••

Laser-assisted localized Si nanowire growth setup



#### **Temperature and time dependent growth of GeNWs**



# **On-demand Vertical GeNW Integration on Si(111)**

#### Location/shape controlled GeNW on a single Si(111) in vertical integration architecture



### **Defect Free Epitaxial Growth of GeNWs on Si (111)**

**Cross sectional HRTEM images of the vertically oriented GeNW on Si (111)** 

#### Laser hydrothermal Growth of ZnO nanowires



In et al., Small (2013)

#### **Growth visualization and control**



### **Graphene patterning and transferring**



### **Graphene devices**









# Beyond graphene Laser annealed MoS<sub>2</sub> transistors on plastic



Choi, Kwon et al. IMID (2013)



#### Digital Direct Metal Patterning (DDMP) Process on a Flexible Substrate

![](_page_20_Picture_1.jpeg)

# **Laser Sintering Examples**

532nm wavelength, 70mW, CW laser, 4" wafer size, 2 m/s scanning speed Room temperature, ambient pressure, Non-vacuum process, maskless process

![](_page_21_Picture_2.jpeg)

High resolution metal features ( total processing time: ~ 7 mins) (down to several microns) 16,000 OFETs on a PI substrate, 3 layered structures (PI substrate/ gate electrode / PVP / source & drain electrodes) ( total processing time: ~ 10 mins)

#### Laser Enabled Wafer scale ZnO Nanoimprinting on Flexible Substrates

![](_page_22_Figure_1.jpeg)

# Fiber scaffold fabrication via 2PP (two-photon polymerization)

Low N.A. objective	

#### Fiber scaffold fabrication

Jeon et al., *Biomed. Microdev.* (2011)

![](_page_25_Picture_0.jpeg)

# Laser ablation nanofabrication

substrate

1. silane modified quartz substrate

![](_page_26_Figure_3.jpeg)

![](_page_26_Picture_4.jpeg)

5. conjugate biotinylated peptide

![](_page_26_Picture_6.jpeg)

Jeon et al., JACS 133 (2011)

#### **2D pitch gradient pattern**

![](_page_27_Picture_1.jpeg)

## 2D pitch gradient pattern

![](_page_28_Picture_1.jpeg)

#### **3D 2PP nanofabrication examples**

![](_page_29_Figure_1.jpeg)

25 layer photonic crystal – periodicity of 400nm

Multi-scale biomimetic structure

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